



4th Position Sensitive Germanium Detectors and Application Workshop (PSeGe)

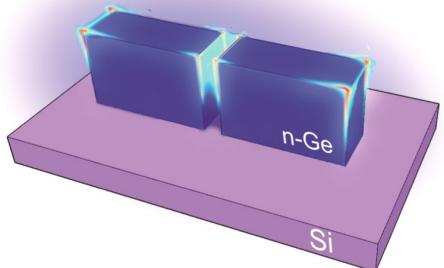
16-19 September 2019 – INFN LNL

**n-type high doping of Ge by Sb
deposition and pulsed laser melting**

Carraro Chiara

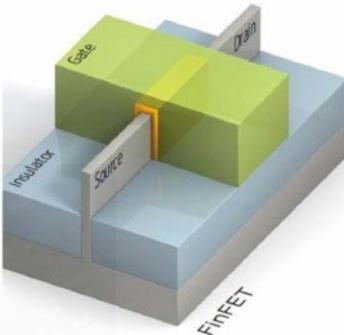
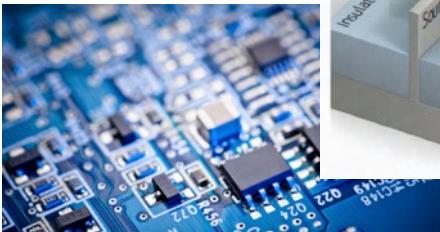
PhD student Physics – Univ. Of Padova

Ge-based devices

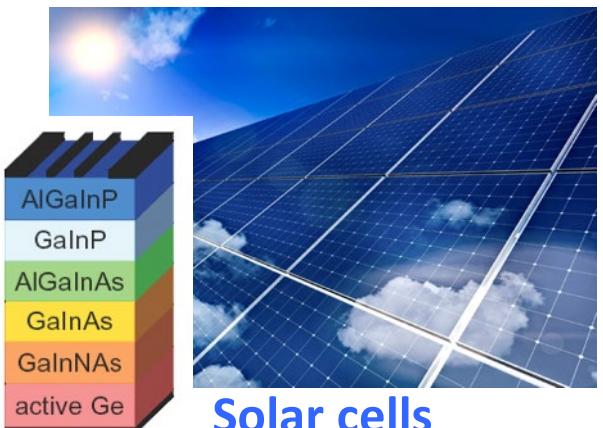
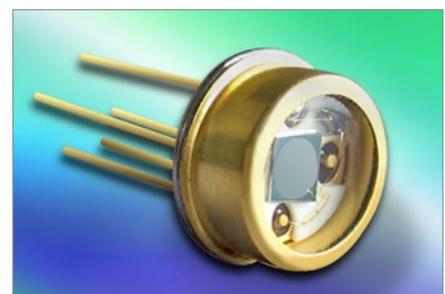


Plasmonic molecular
sensors

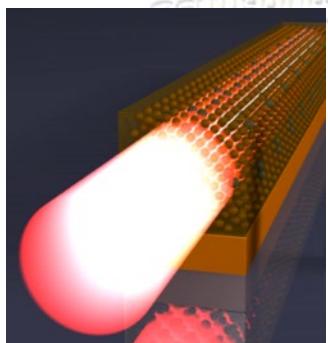
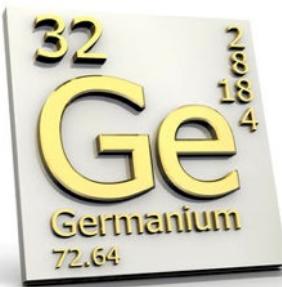
Nanoelectronics



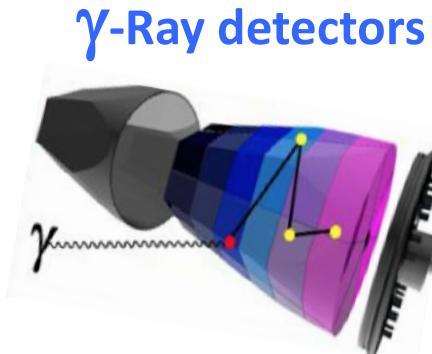
Photodetectors



Solar cells

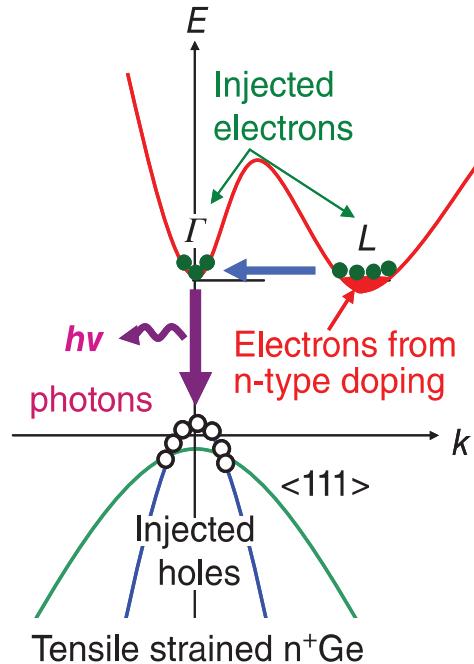
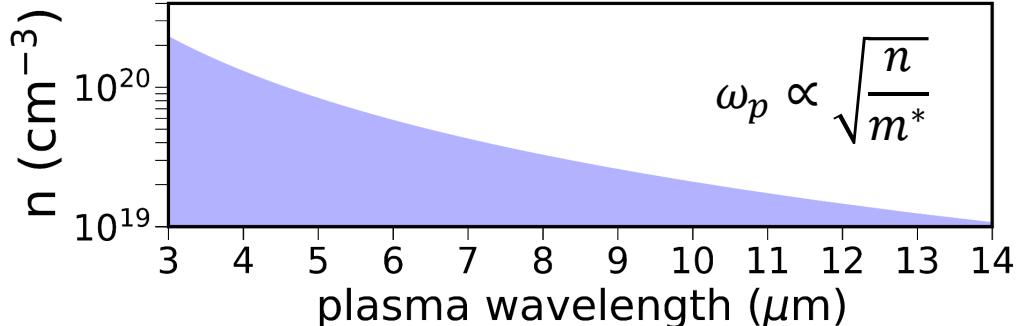
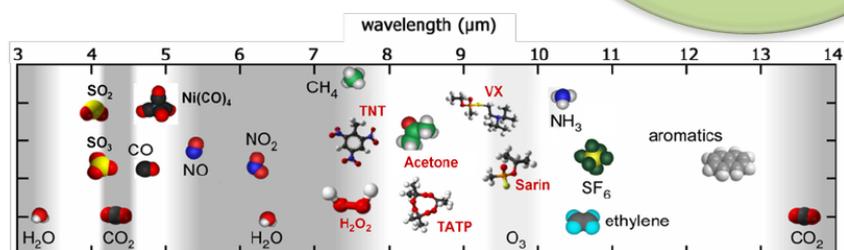
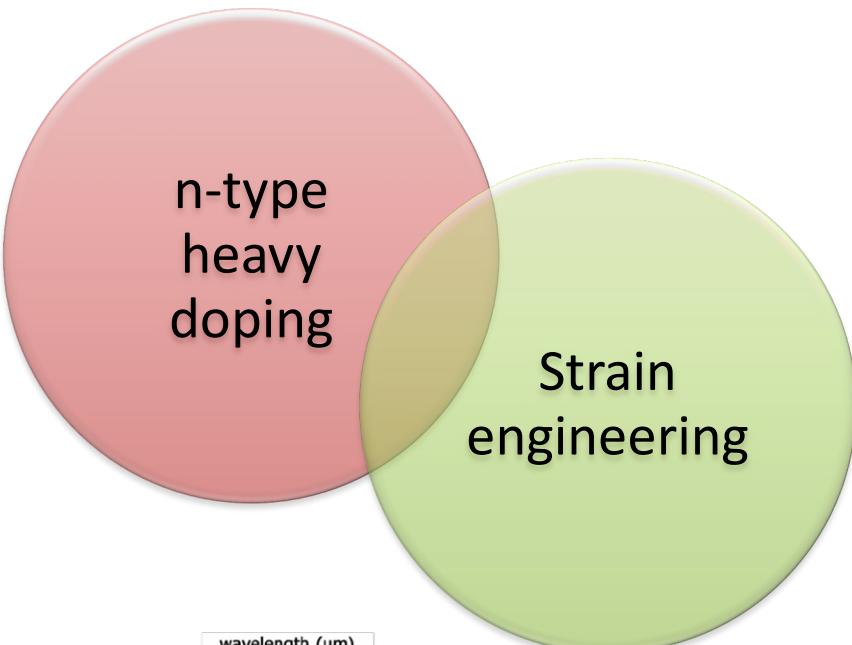
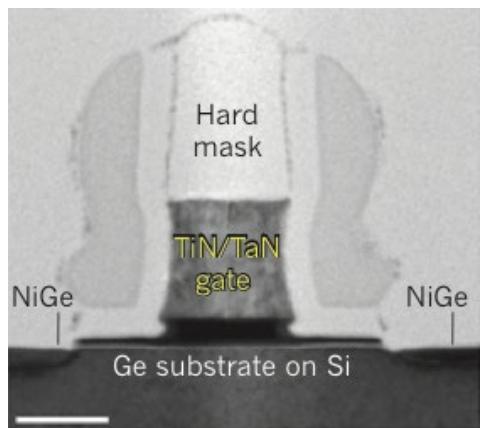


Lasers

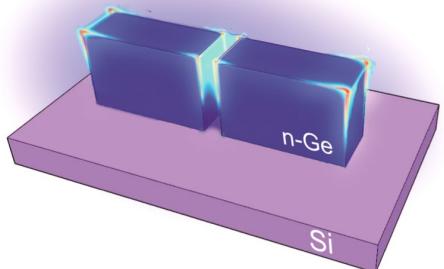


γ-Ray detectors

Ge hot topics

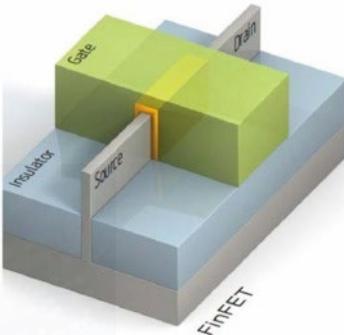
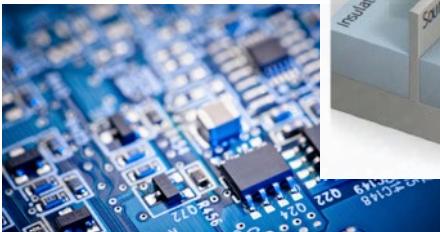


Ge-based devices

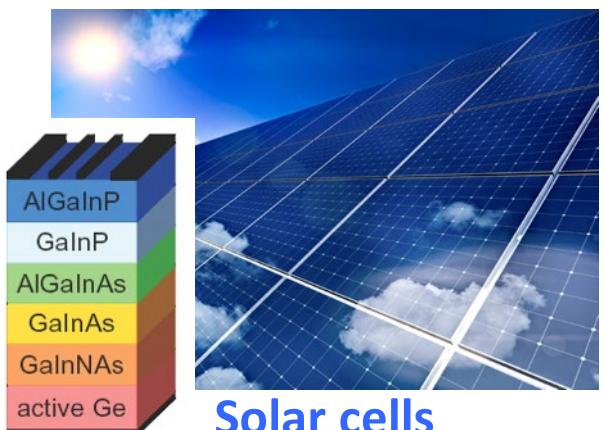
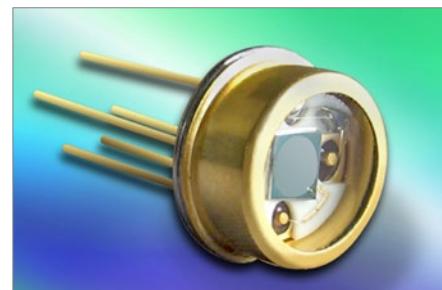


Plasmonic molecular
sensors

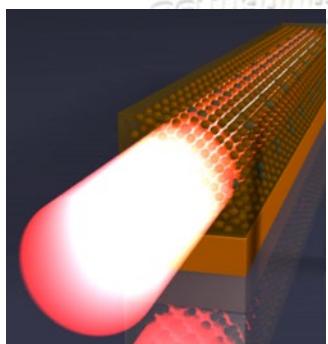
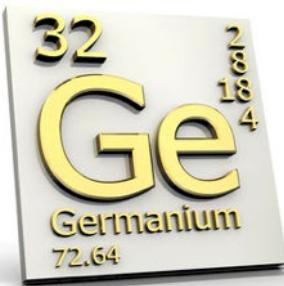
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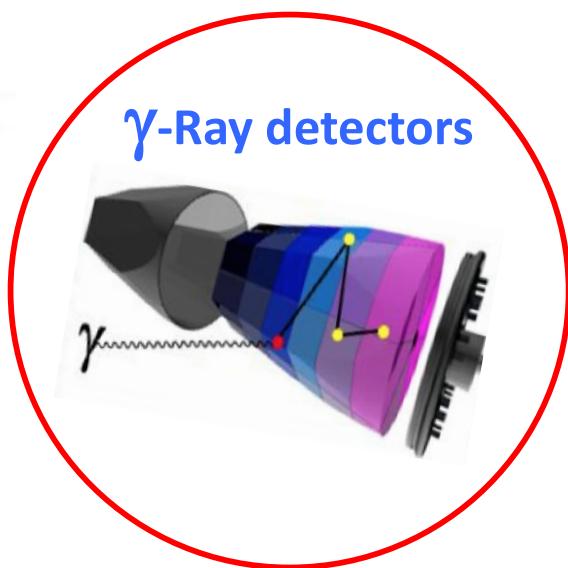
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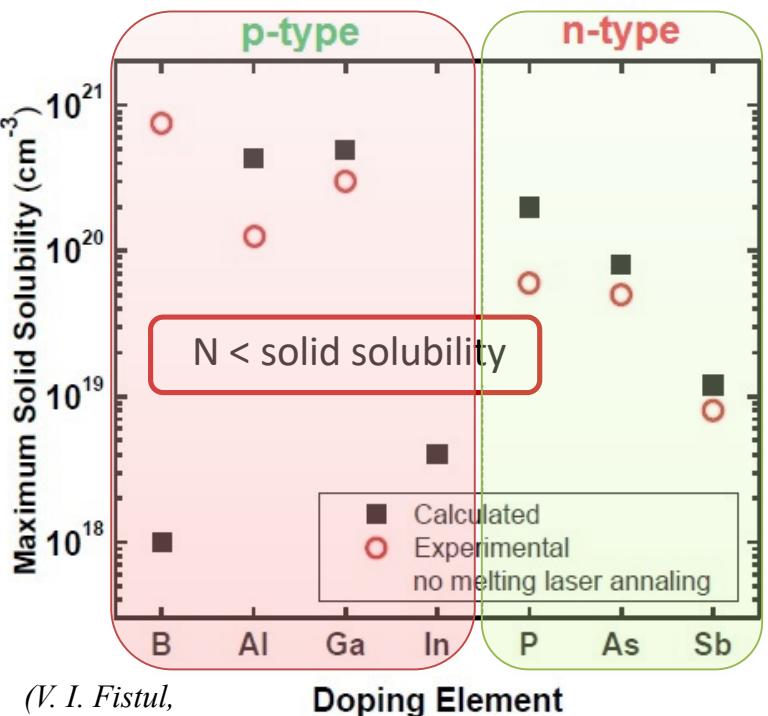
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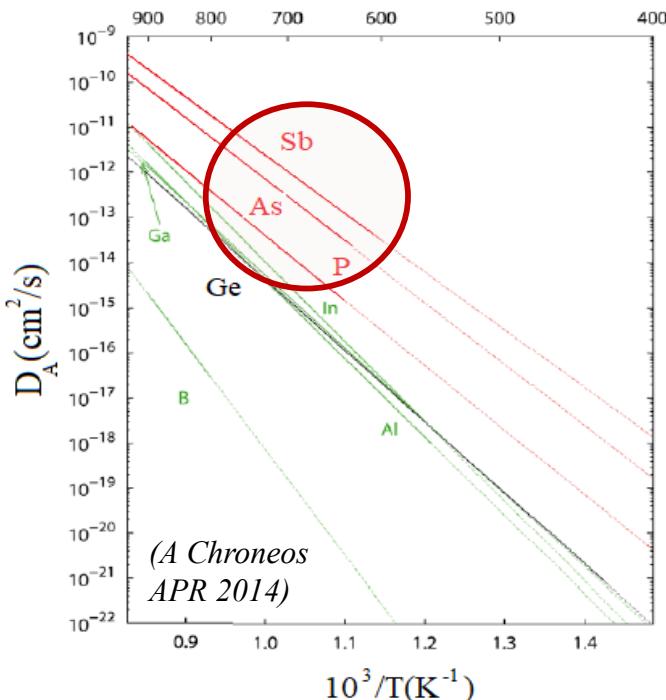
γ -Ray detectors

Issues on Ge n-type doping

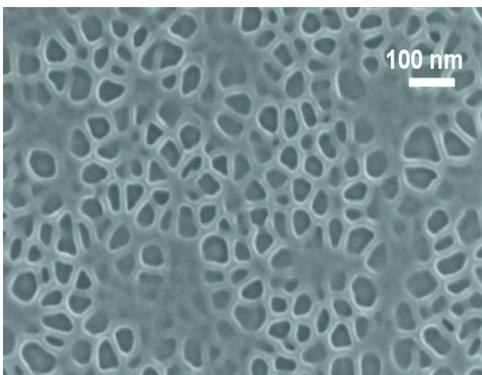
Low active concentrations



High Diffusivities

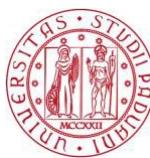


Ion Implantation Damage

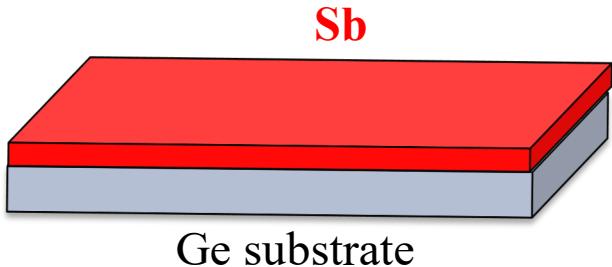


Ge implanted with 50 KeV $6 \times 10^{15} \text{ Sb}/\text{cm}^2$
(Bruno JAP 2010)

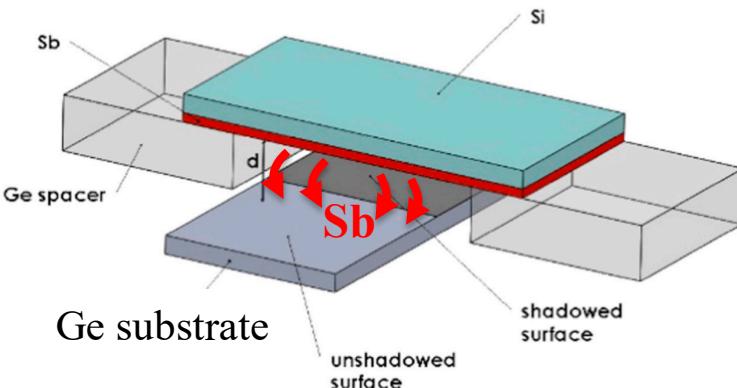
Sb deposition + PLM



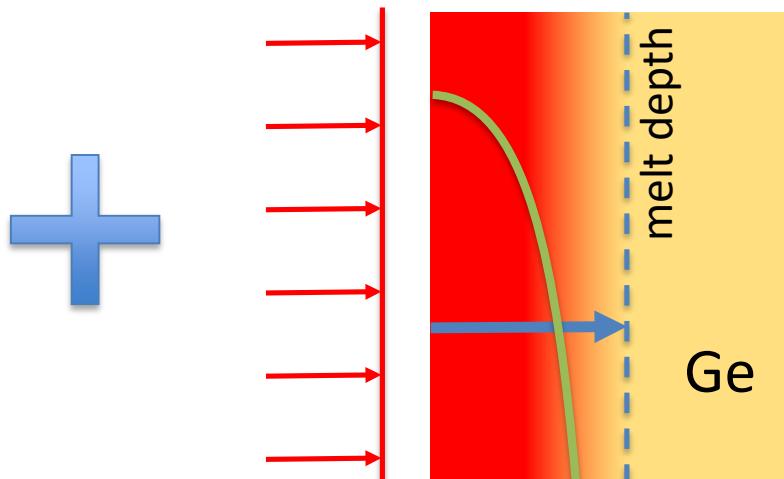
Sb Sputtering (1 – 8 nm)



Sb RTP Evaporation (self-limited monolayer deposition)



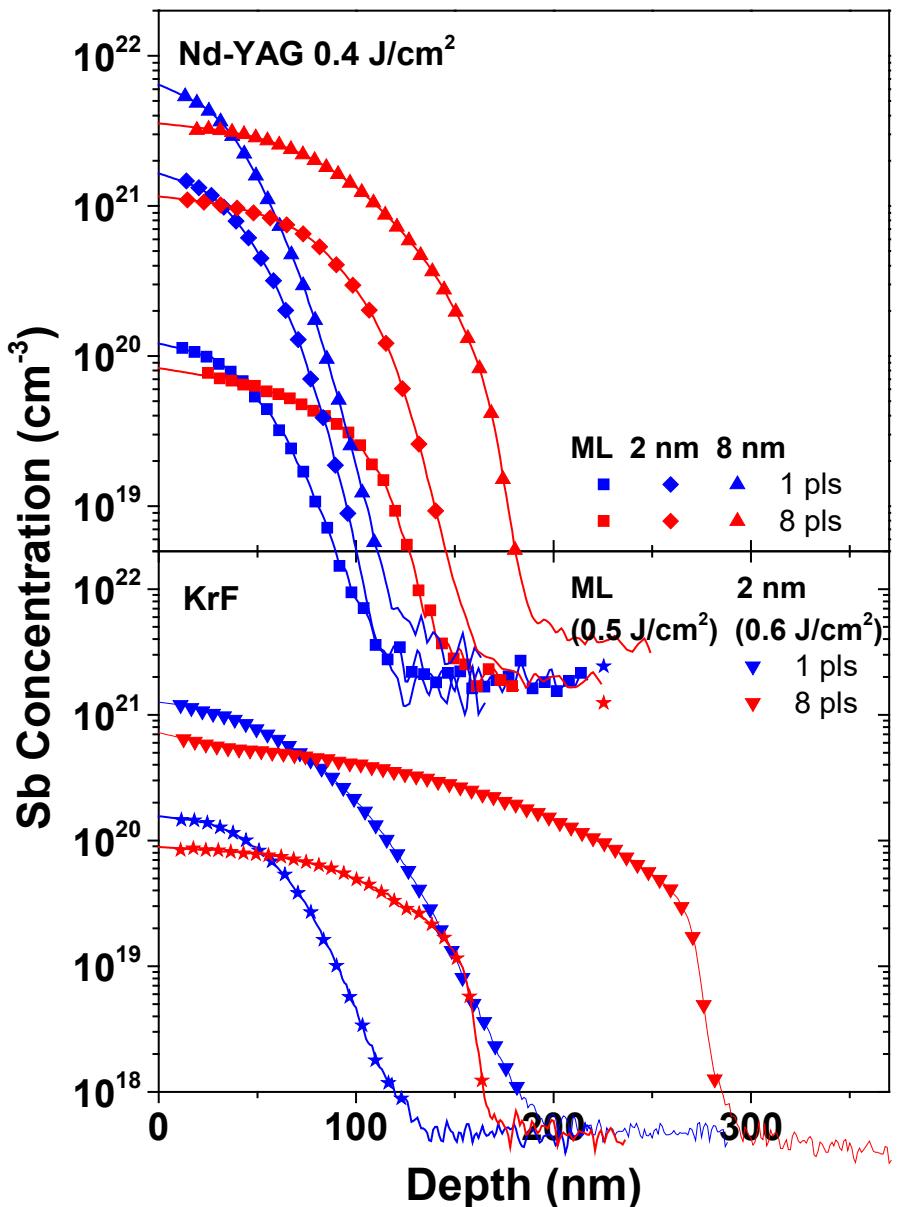
(F. Sgarbossa et al., Appl. Surf. Sci. 496 (2019))



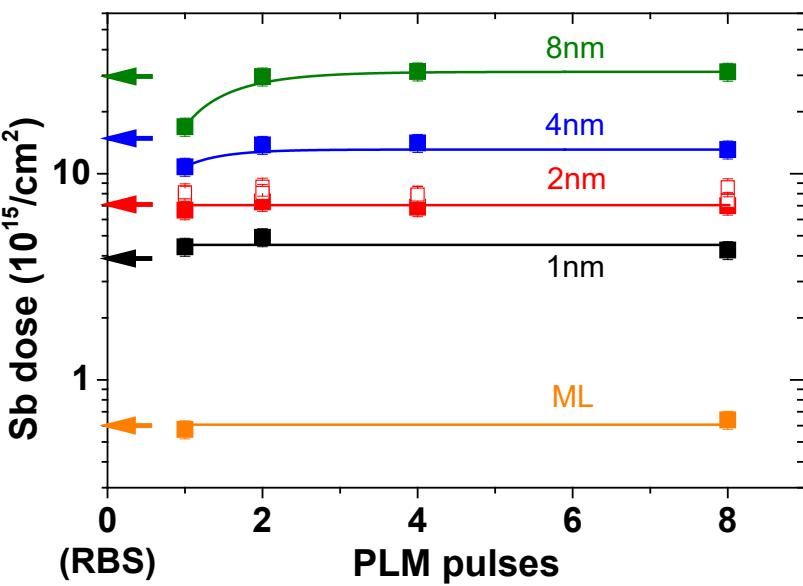
Pulsed Laser Melting for dopant diffusion, incorporation, and activation

- Nd-YAG $\lambda=355$ nm, 7 ns, 400 mJ/cm²
1 to 8 pulses
- KrF $\lambda=248$ nm, 25 ns, 300-700 mJ/cm²
1 to 8 pulses

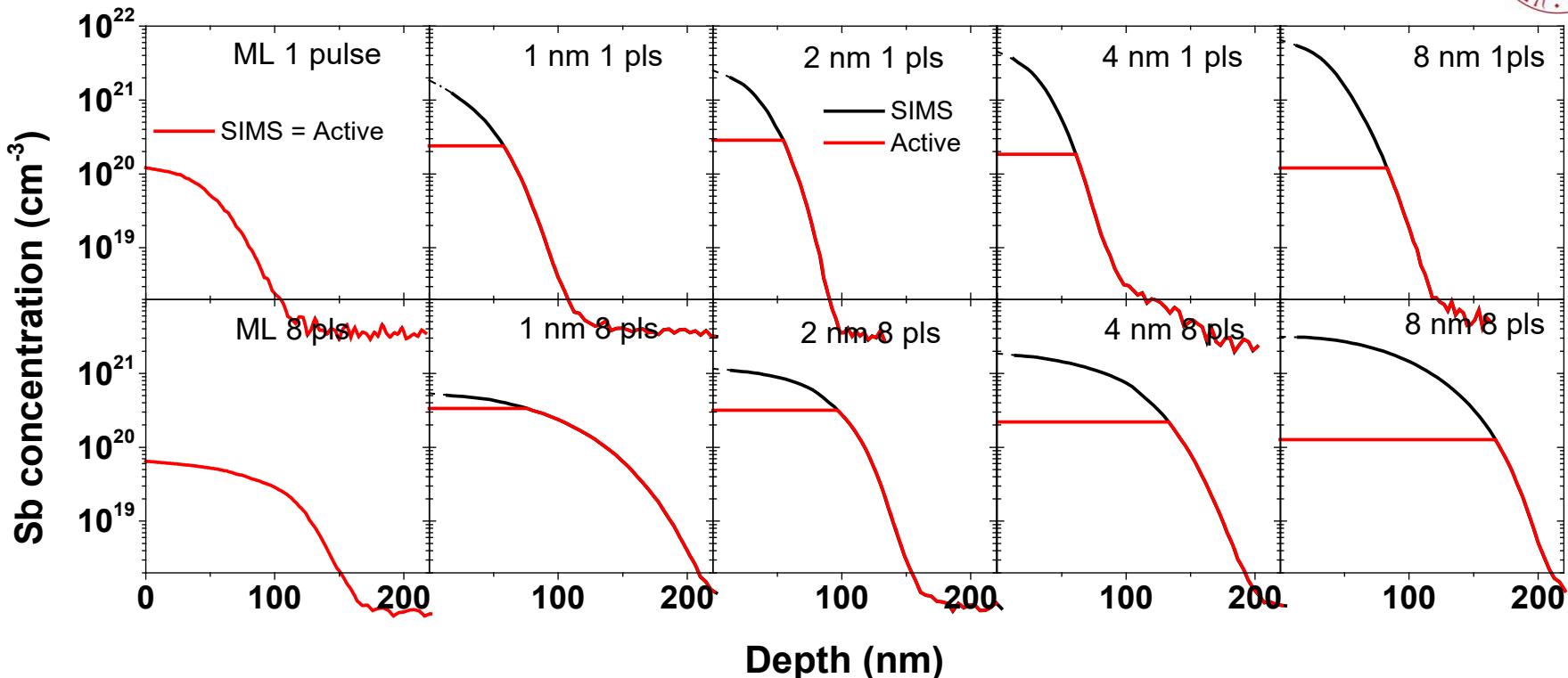
Chemical profile evolution



- Sb incorporation at >10% concentration
- No surface segregation
- No Sb loss
- Diffusion confined in molten layer



Dopant activation

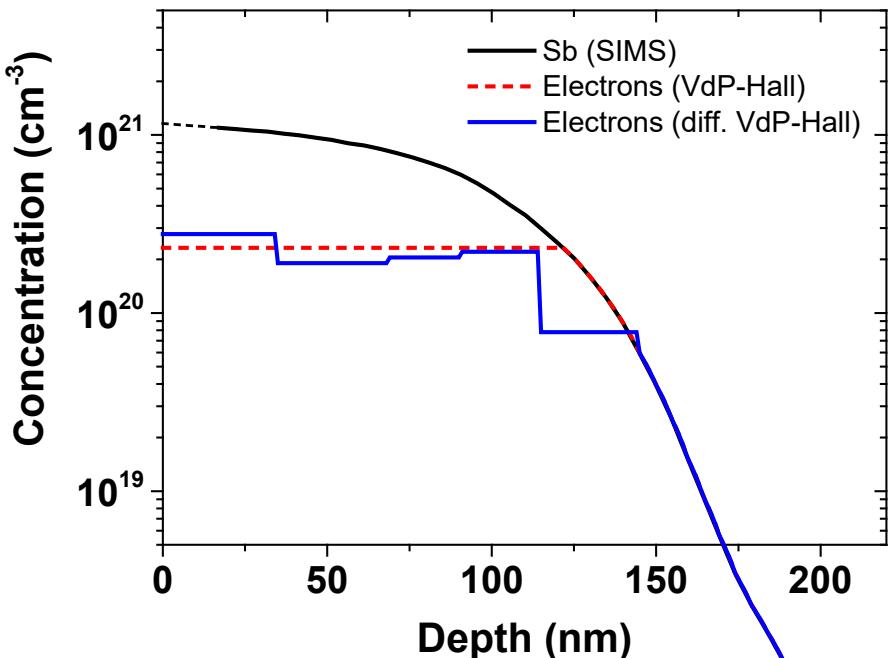


- Van der Pauw – Hall measurements
- Maximum active concentration extracted from measured RHs assuming SIMS profiles fully active below N_{\max}
- Hall scattering factor $r_H=1$

$$RH_s = \frac{\int n(x) \mu^2(x) dx}{e \cdot \left(\int n(x) \mu(x) dx \right)^2}$$

(R. Baron, G. Shifrin, O. Marsh and J. W. Mayer, and J. Menéndez, J. Appl. Phys. **40**, 3702 (1969))

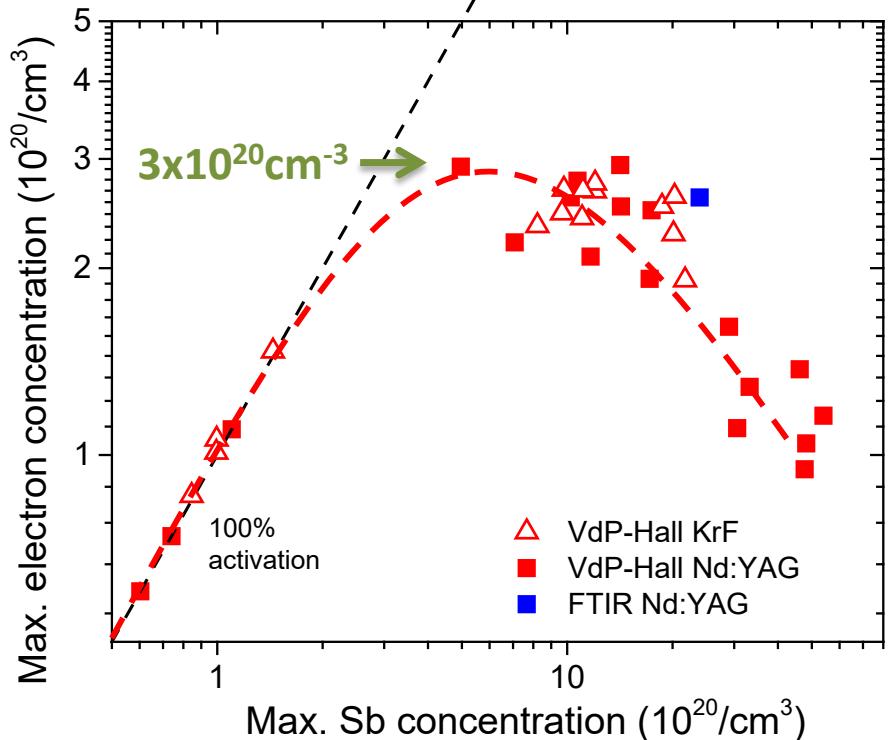
Dopant activation



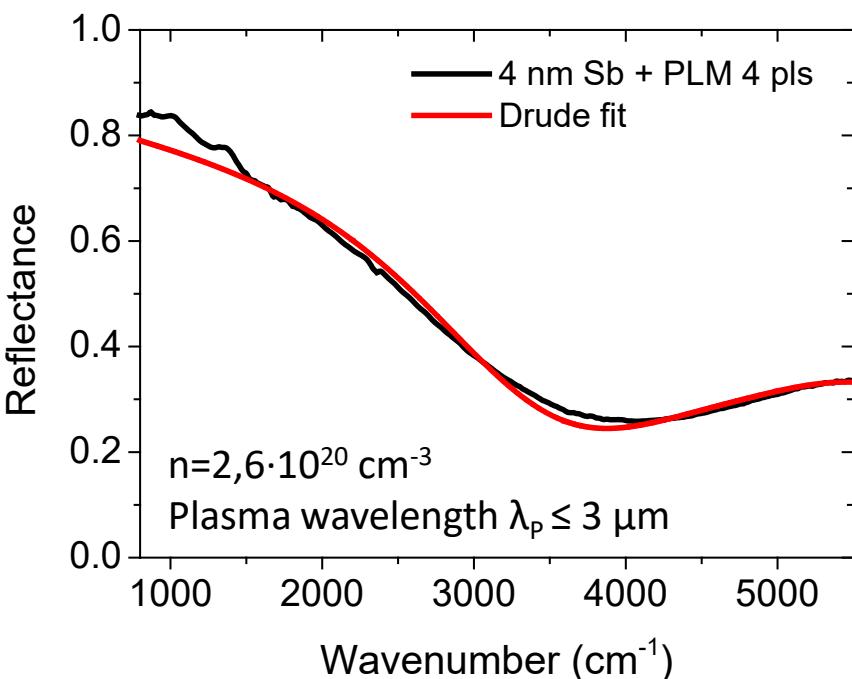
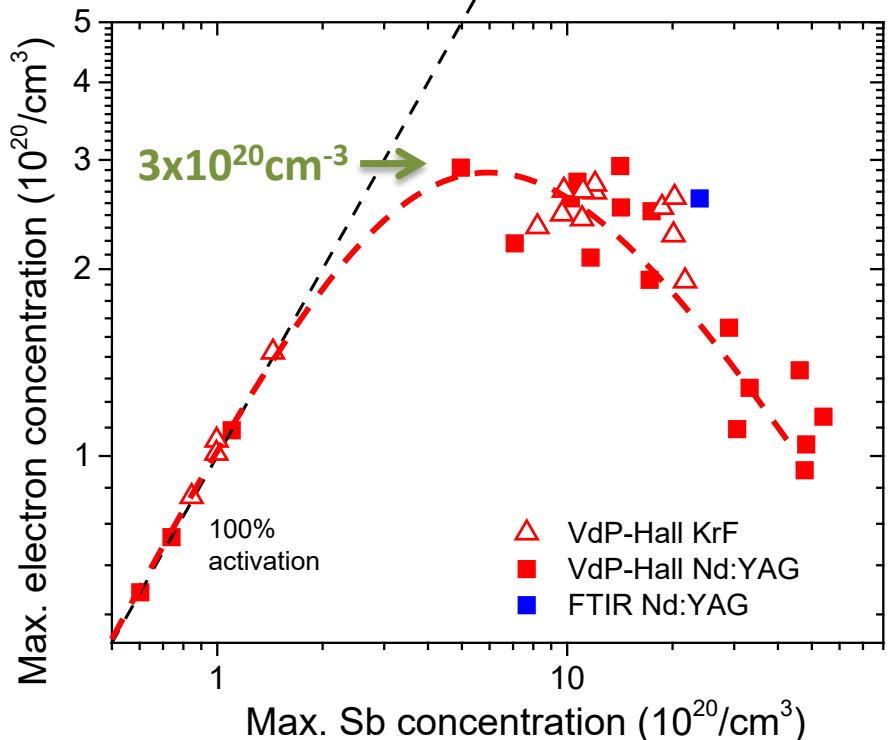
- Alternating VdP-Hall measurements with chemical etching → carrier depth profile
- Differential Van der Pauw – Hall measurements confirm active profile.

$$n(x) = \frac{(\Delta\sigma_S)^2}{q \cdot \Delta x \cdot \Delta(RH_S\sigma_S^2)}$$
$$\mu_H(x) = \frac{\Delta(RH_S\sigma_S^2)}{\Delta\sigma_S}$$

Dopant activation

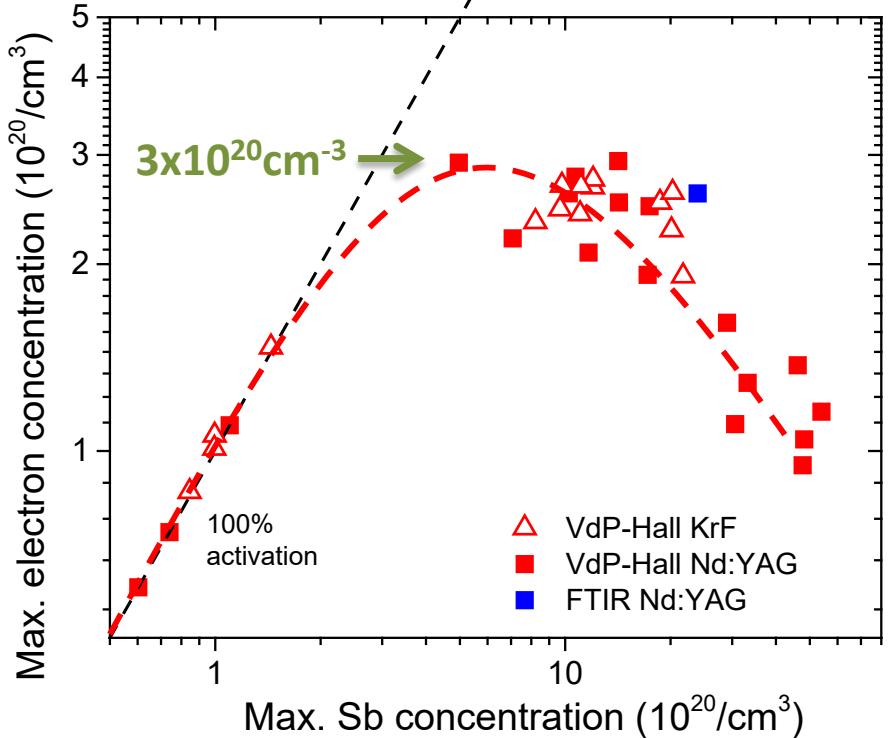


- Active Sb saturates at $3 \times 10^{20} \text{ cm}^{-3}$

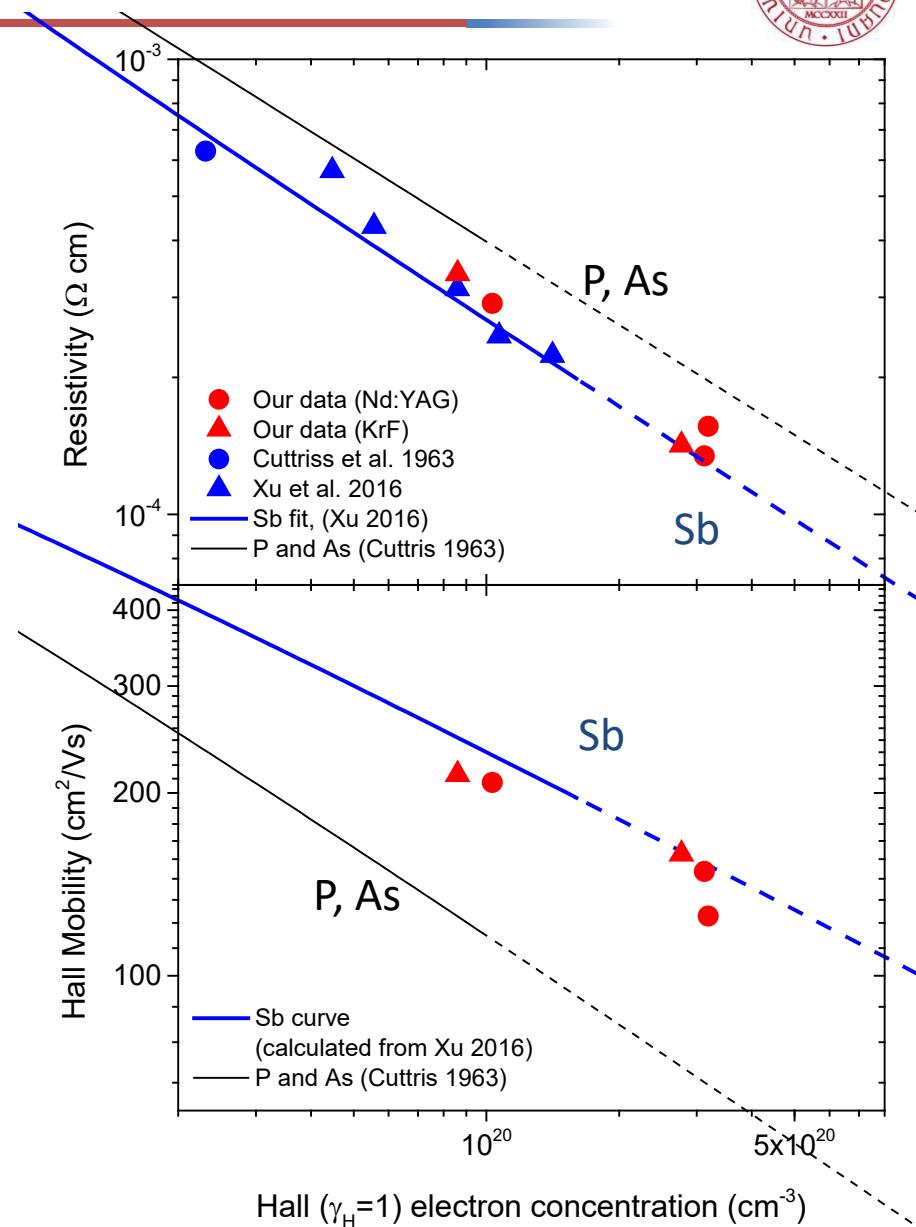


- Active Sb saturates at $3 \times 10^{20} \text{ cm}^{-3}$
- Plasma wavelength below $3 \mu\text{m}$

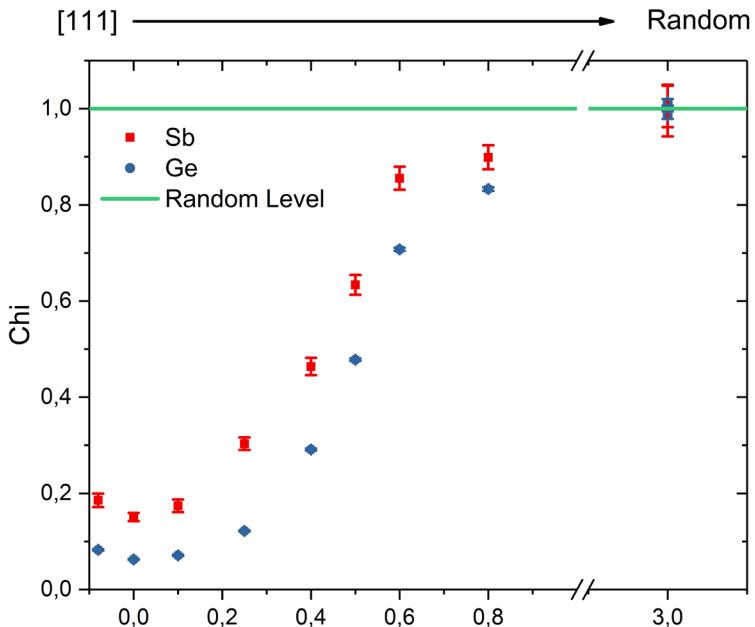
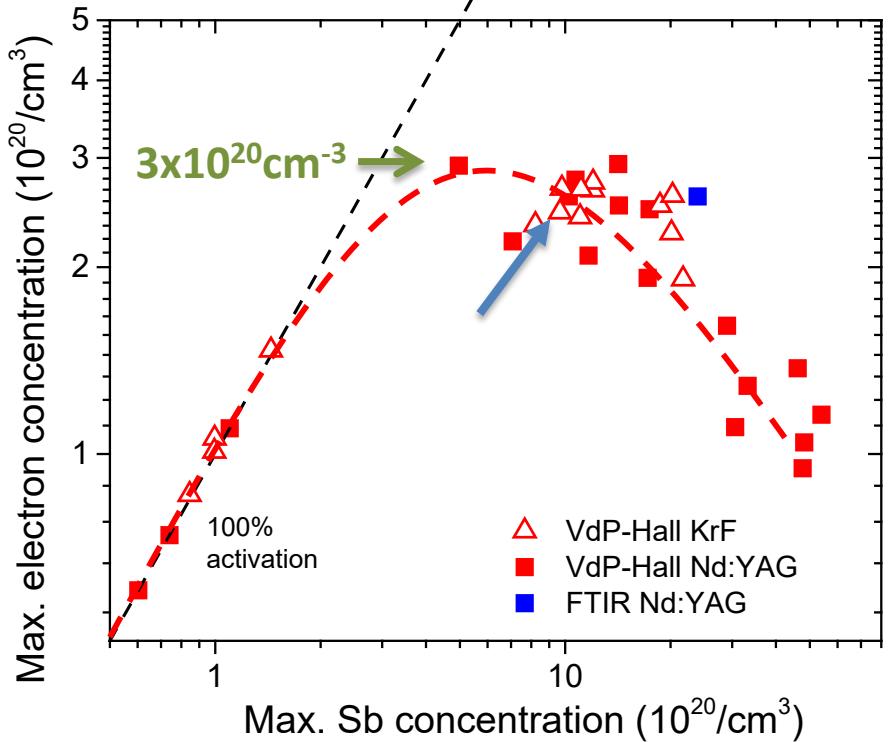
Resistivity and Mobility



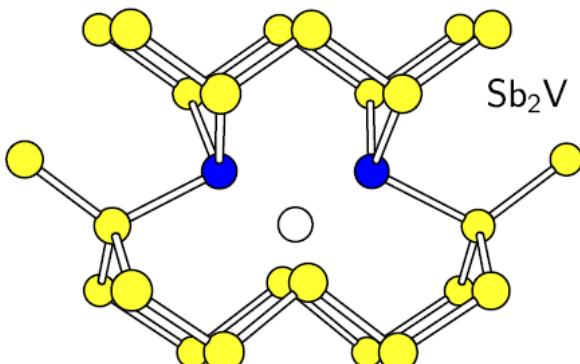
- Active Sb saturates at $3 \times 10^{20} \text{ cm}^{-3}$
- Plasma wavelength below $3 \mu\text{m}$
- Ultralow resistivity
- High mobility



Substitutionality (c-RBS dip)

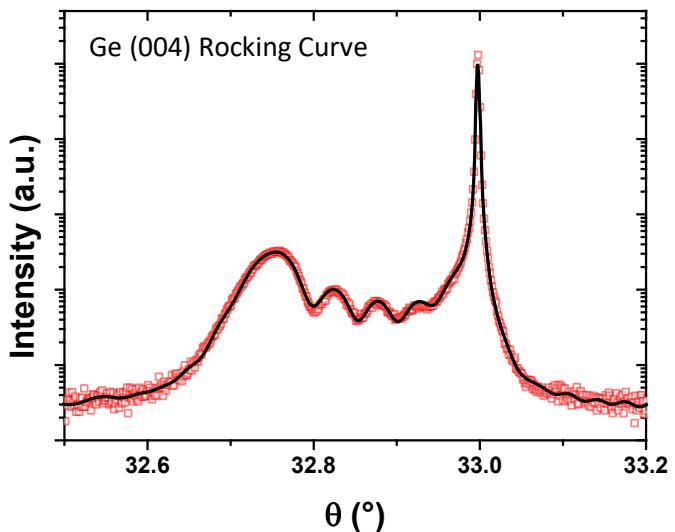
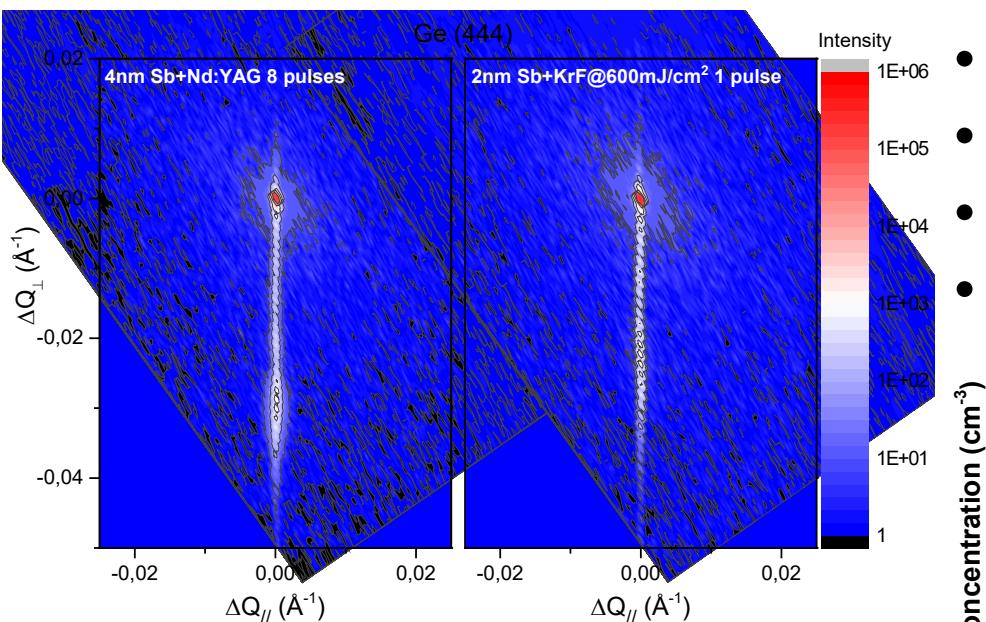


- C-RBS: Sb \sim 100 % nearly substitutional with small displacements
- After PLM inactive Sb is in the form of very small Sb_nV complexes.

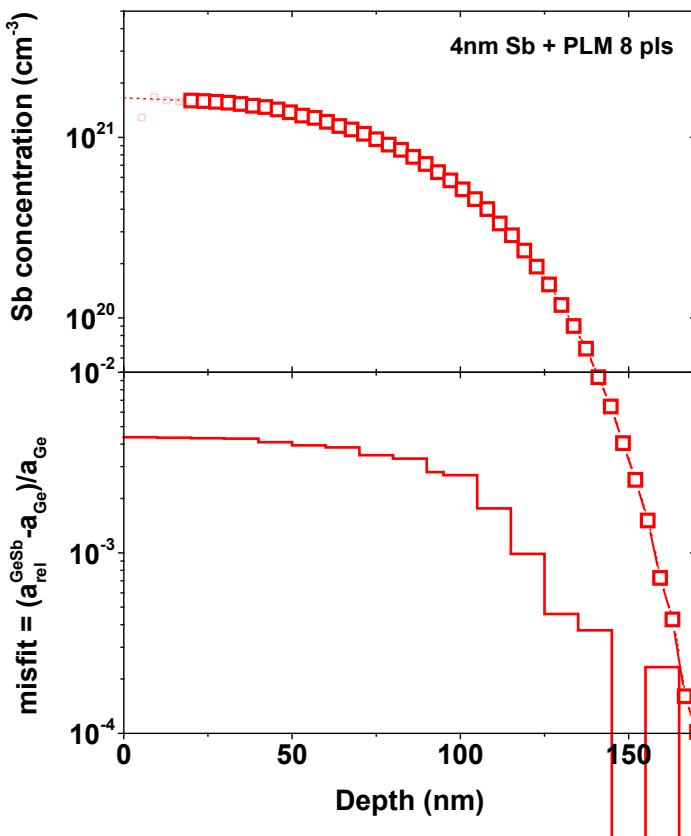


(José Coutinho, et al., J. Mater. Sci. Mater. Electron. 2007)
(A. Chroneos, J. Appl. Phys. 2010)

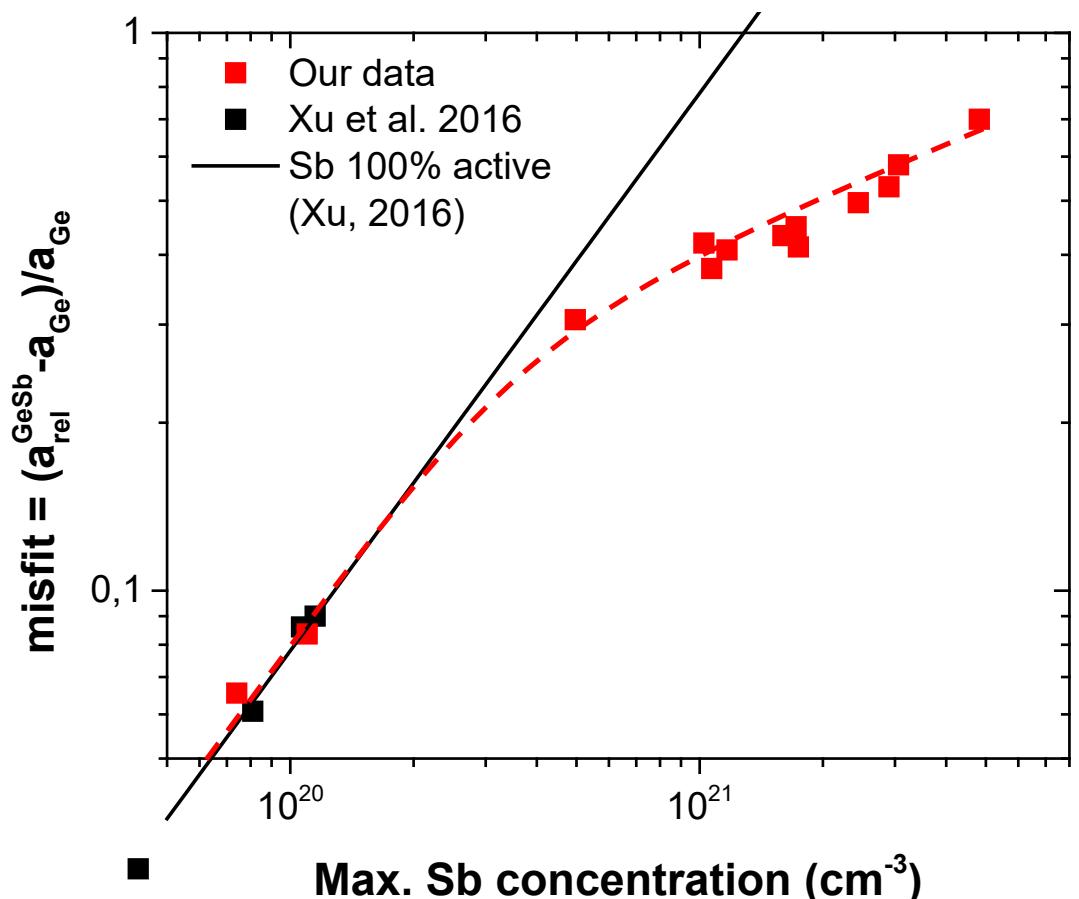
HRXRD strain depth profiling



- Excellent crystallinity
- Pseudomorphicity of doped layer
- No sign of extended defects
- Strain depth profiles extracted



HRXRD strain depth profiling



- At low concentrations misfit aligns with literature data for 100% active Sb
- At high concentrations misfit continue to increase up to 0.7%

Conclusions



- The combination of Sb deposition and PLM provides an extremely efficient doping technique.
- Carrier concentration up to $3 \times 10^{20} \text{ cm}^{-3}$ with record low resistivity and excellent mobility
- No bulk contamination as consequence of PLM

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J. Phys. D: Appl. Phys. 52 (2019) 035104 (11pp)

Journal of Physics D: Applied Physics

<https://doi.org/10.1088/1361-6463/aae9c0>

Characterization and modeling of thermally-induced doping contaminants in high-purity germanium

V Boldrini^{1,2,4}, G Maggioni^{1,2}, S Carturan^{1,2},
R Milazzo¹, D R Napoli², E Napolitani^{1,2}, R C
and D De Salvador^{1,2}

Eur. Phys. J. A (2018) 54: 34
DOI 10.1140/epja/i2018-12471-0

Special Article – New Tools and Techniques

THE EUROPEAN
PHYSICAL JOURNAL A

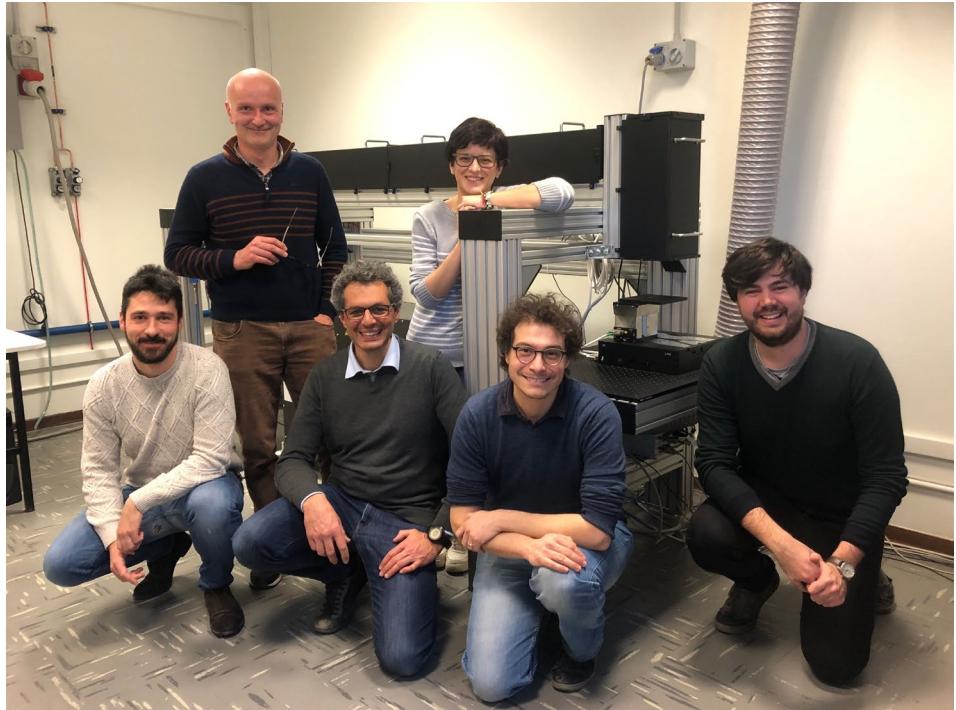
Pulsed laser diffusion of thin hole-barrier contacts in high purity germanium for gamma radiation detectors

G. Maggioni^{1,2,a}, S. Carturan^{1,2}, W. Raniero², S. Riccetto³, F. Sgarbossa^{1,2}, V. Boldrini^{1,2}, R. Milazzo¹,
D.R. Napoli², D. Scarpa², A. Andriguetto², E. Napolitani^{1,2}, and D. De Salvador^{1,2}

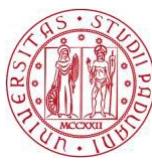
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- The combination of Sb deposition and PLM provides an extremely efficient doping technique.
- Carrier concentration up to $3 \times 10^{20} \text{ cm}^{-3}$ with record low resistivity and excellent mobility
- No bulk contamination as consequence of PLM
- Pseudomorphic layers Ge:Sb layers with no extended defects
- FTIR reports plasma wavelengths below $3 \mu\text{m}$ in the MIR range useful for gas sensing applications
- Inactive Sb is nearly substitutional with small displacement, compatible with very small Sb_nV clusters.



**Thanks for your
attention!**





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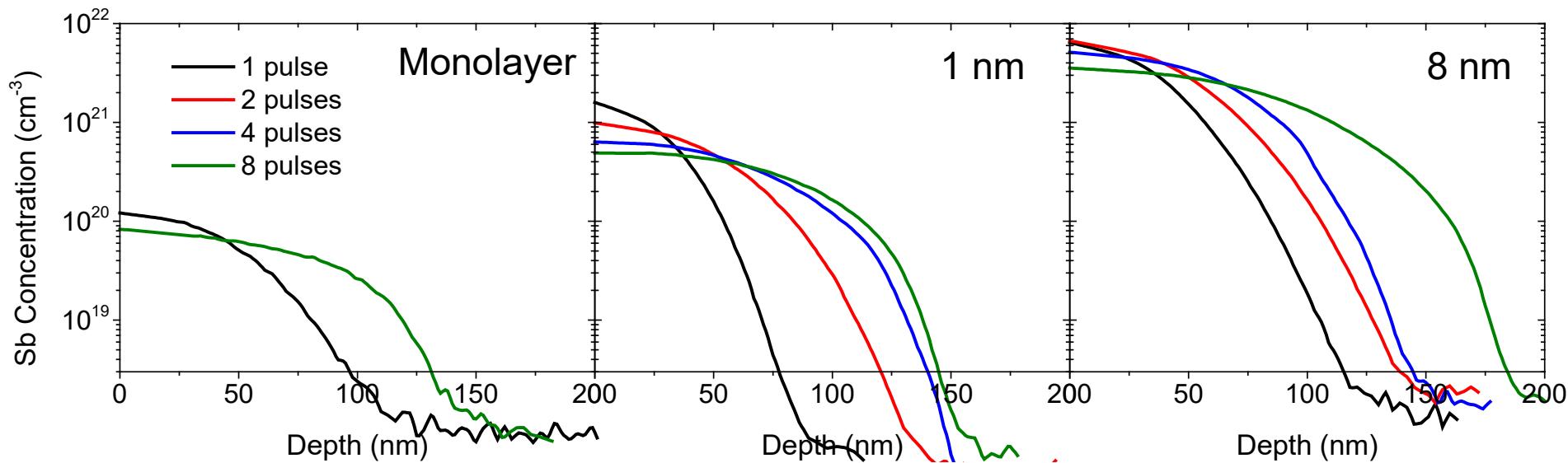
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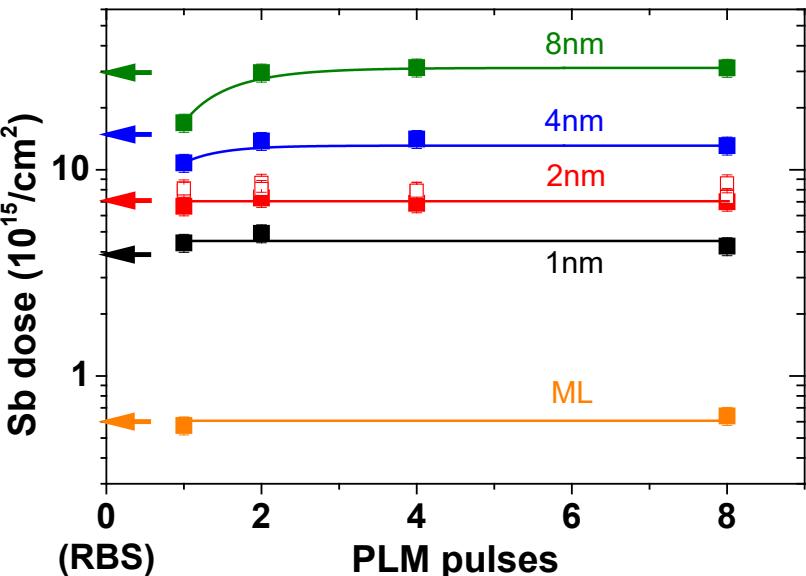
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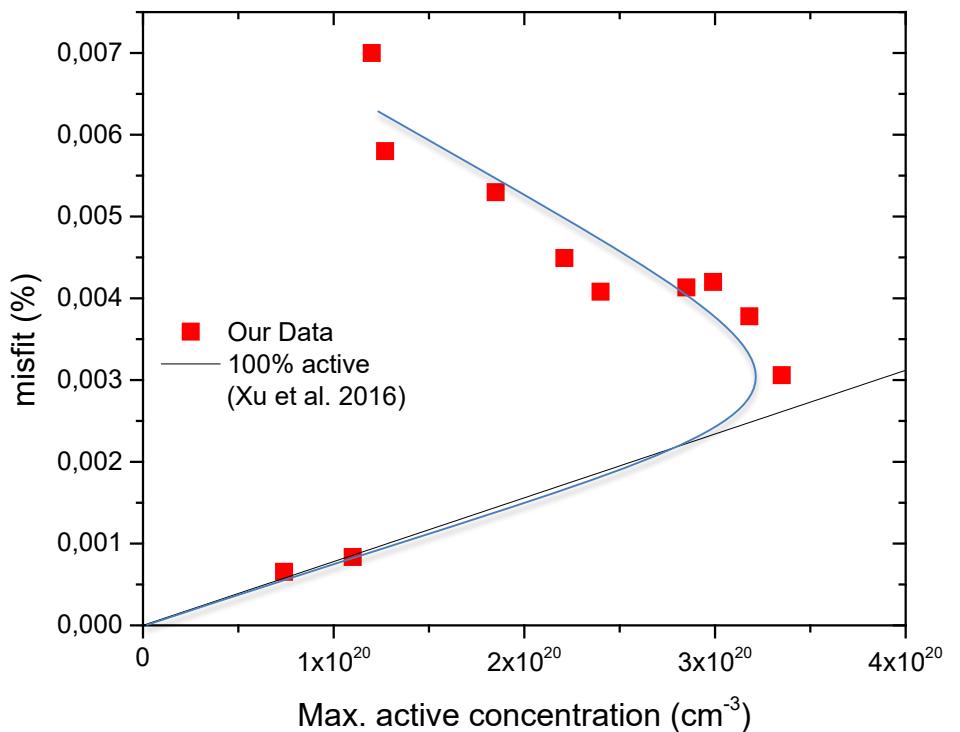
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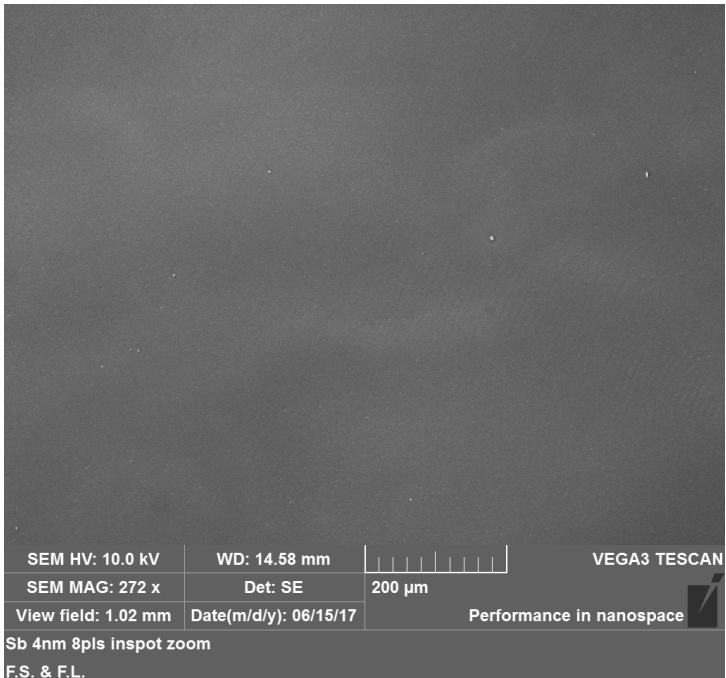
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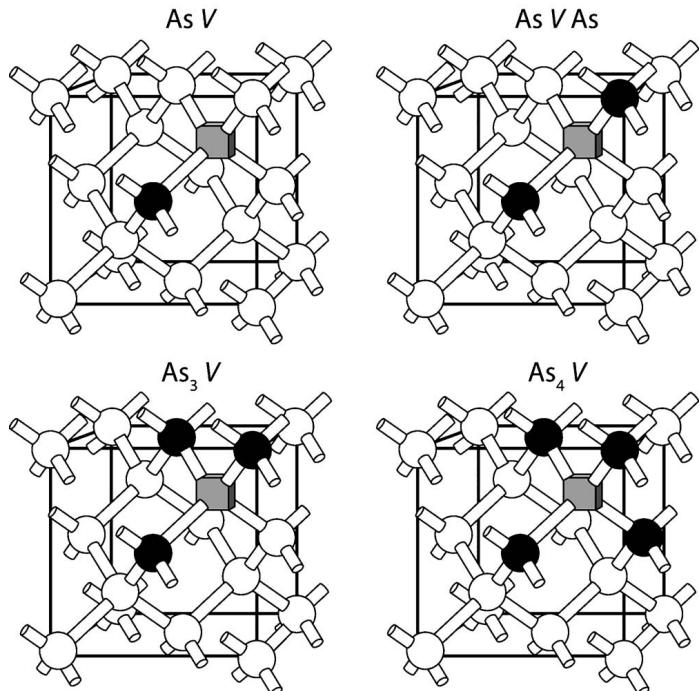


FIG. 1. As_nV configurations in a unit cell of the Ge. White circles represent the Ge atoms, black circles the As atoms, and squares V.

A. Chroneos, R. W. Grimes, B. P. Uberuaga, S. Brotzmann, and H. Bracht, *Appl. Phys. Lett.* **91**, 192106 (2007).

